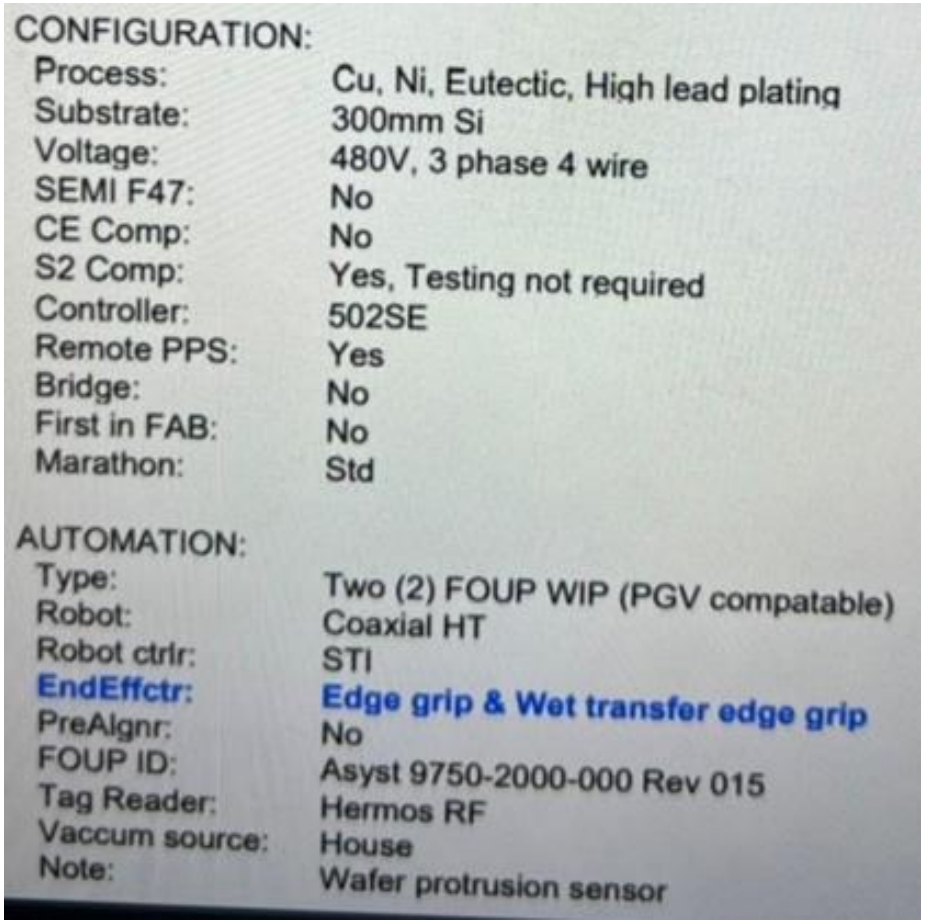


Semitool Raider
Model: RE12F2ECD1204

Semitool Raider system, 300mm.

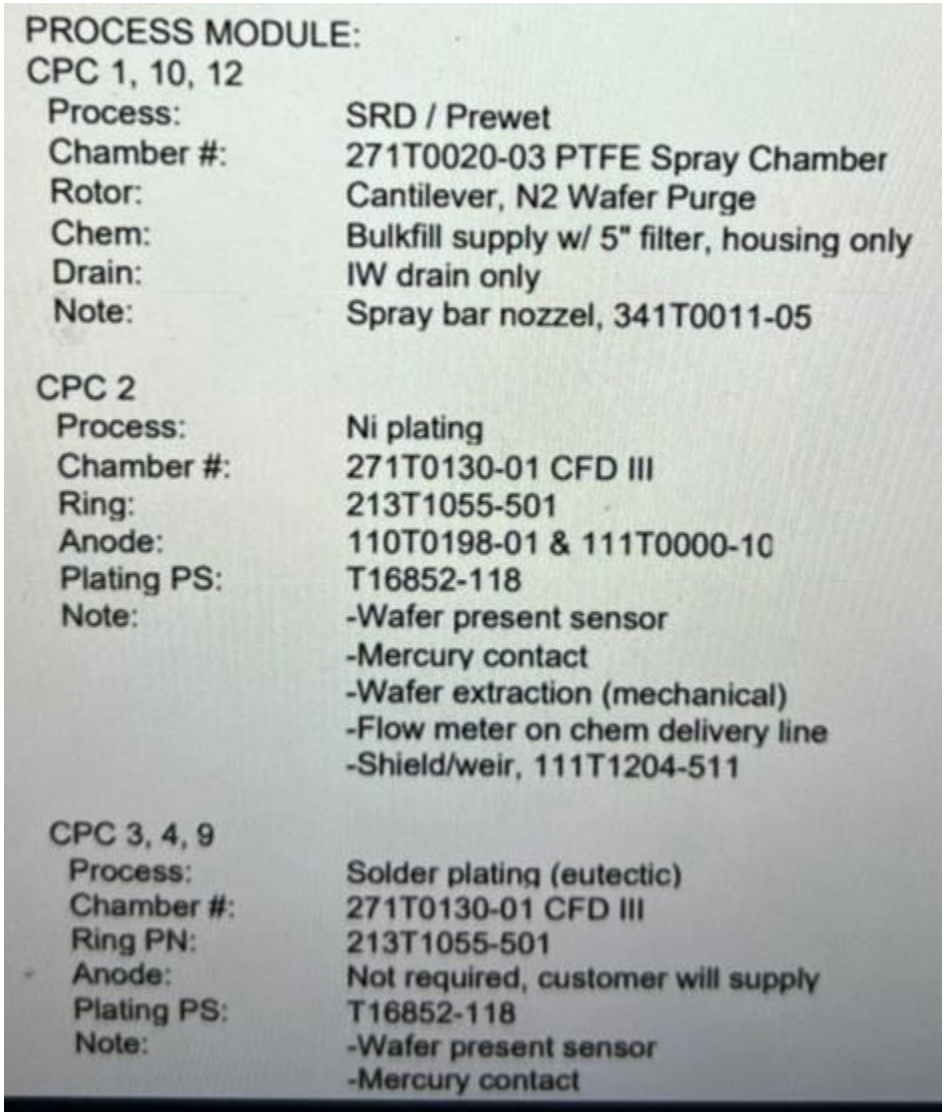


CONFIGURATION:

Process:	Cu, Ni, Eutectic, High lead plating
Substrate:	300mm Si
Voltage:	480V, 3 phase 4 wire
SEMI F47:	No
CE Comp:	No
S2 Comp:	Yes, Testing not required
Controller:	502SE
Remote PPS:	Yes
Bridge:	No
First in FAB:	No
Marathon:	Std

AUTOMATION:

Type:	Two (2) FOUP WIP (PGV compatable)
Robot:	Coaxial HT
Robot ctrlr:	STI
EndEffctr:	Edge grip & Wet transfer edge grip
PreAlgnr:	No
FOUP ID:	Asyst 9750-2000-000 Rev 015
Tag Reader:	Hermos RF
Vaccum source:	House
Note:	Wafer protrusion sensor



PROCESS MODULE:

CPC 1, 10, 12

Process:	SRD / Prewet
Chamber #:	271T0020-03 PTFE Spray Chamber
Rotor:	Cantilever, N2 Wafer Purge
Chem:	Bulkfill supply w/ 5" filter, housing only
Drain:	IW drain only
Note:	Spray bar nozzel, 341T0011-05

CPC 2

Process:	Ni plating
Chamber #:	271T0130-01 CFD III
Ring:	213T1055-501
Anode:	110T0198-01 & 111T0000-10
Plating PS:	T16852-118
Note:	-Wafer present sensor -Mercury contact -Wafer extraction (mechanical) -Flow meter on chem delivery line -Shield/weir, 111T1204-511

CPC 3, 4, 9

Process:	Solder plating (eutectic)
Chamber #:	271T0130-01 CFD III
Ring PN:	213T1055-501
Anode:	Not required, customer will supply
Plating PS:	T16852-118
Note:	-Wafer present sensor -Mercury contact

CPC 5, 6, 7, 8

Process:	Solder plating (high lead)
Chamber #:	271T0130-01 CFD III
Ring:	213T1055-501
Anode:	Not required, customer will supply
Plating PS:	T16852-118
Note:	-Wafer present sensor -Mercury contact -Wafer extraction (mechanical) -Flow meter on chem delivery line -Shield/weir, 111T1204-511

CPC 11

Process:	Cu plating
Chamber #:	271T0130-01 CFD III
Ring:	213T1055-501
Anode:	111T1197-01
Plating PS:	T16852-118
Note:	-Wafer present sensor -Mercury contact -Wafer extraction (mechanical) -Flow meter on chem delivery line -Shield/weir, 111T1204-511

Size:	48L
Style:	Unsealed NPP
H/C:	Heat Exchange Coils
Temp:	50 - 55C
Circ:	Recirc / reclaim
Filter:	10", housing only
Lvl Snsr:	Floats (5)
Delivery pump:	Levtronix BPS 3
Maint pump:	WK AP50
Supply:	ARU / CDU / Bulkfill / Manual fill tube
Sample Prt:	Yes
Delivery:	CPC 2
Chem:	Ni Plating Solution
Note:	-Carbon polishing filter -Conditioning Electrodes -pH monitor -Filter drain to be selectable to drain to tank or drain -Manual shutoff valve between tank and pump -Power supply (T16852-06B) -Sight tube

Tank 2, High Lead Solder

Size:	120L
Style:	Unsealed NPP
H/C:	Heat Exchange Coils
Temp:	25 - 35C

Temp:	25 - 35C
Circ:	Recirc
Filter:	10", housing only
Lvl Snsr:	Floats (5)
Delivery pump:	Levtronix BPS 3
Maint pump:	WK AP50
Supply:	Bulkfill/CDU / Manual fill tube
Sample Prt:	Yes
Delivery:	CPC 5, 6, 7, 8
Chemical:	High Lead plating Solution
Note:	-Manual shutoff valve between tank and pump -Sight tube

Tank 3, Eutectic Solder

Size:	120L
Style:	Unsealed NPP
H/C:	Heat Exchange Coils
Temp:	25 - 35C
Circ:	Recirc / reclaim
Filter:	10", housing only
Lvl Snsr:	Floats (5)
Delivery pump:	Levtronix BPS 3
Maint pump:	WK AP50
Supply:	Bulkfill/CDU / Manual fill tube
Sample Prt:	Yes
Delivery:	CPC 3, 4, 9
Chemical:	Eutectic plating Solution
Note:	-Manual shutoff valve between tank and pump -Sight tube

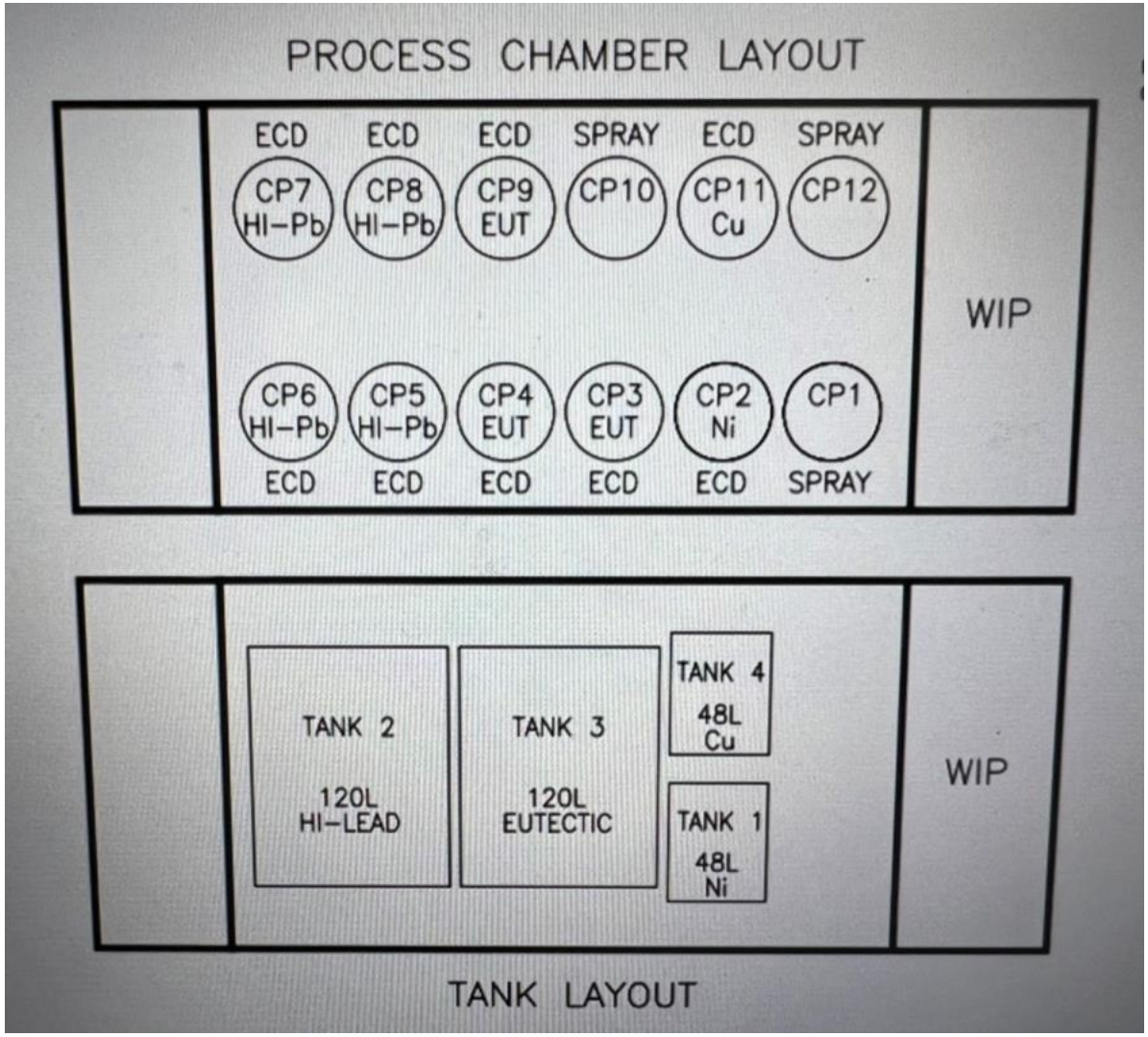
Tank 4, Cu

Size:	48L
Style:	Unsealed NPP
H/C:	Heat Exchange Coils
Temp:	25C
Circ:	Recirc / reclaim
Filter:	10", housing only
Lvl Snsr:	Floats (5)
Delivery pump:	Levtronix BPS 3
Maint pump:	WK AP50
Supply:	ARU / CDU / Bulkfill / Manual fill tube
Sample Prt:	Yes
Delivery:	CPC 11
Chemical:	Cu plating Solution
Note:	-Manual shutoff valve between tank and pump -Sight tube

DRAINS:
- -IW
- -Eutectic
- -Hi-Lead
- -Ni
- -Cu

OPTIONS
- -Heater, Chiller (qty 3)
- -AARU
- -DI booster pump cabinet and Interface (do not supply pump)

SPECIALS:
- -Plating Power Supply rack (external)
- -CDRU & AARU interface
- -CCD camera (qty 6) -w- DVR
- -Interconnect cables for connections from Raider tool to ancillary equipment to be 75ft single piece cables. (to include CDRU, AARU, ethernet, ect)
- -Supply AARU & CDRU cables (20 meter length)


PROCESS CHAMBER LAYOUT
ECD
ECD
ECD
SPRAY
ECD
SPRAY
CP7 HI-Pb
CP8 HI-Pb
CP9 EUT
CP10
CP11 Cu
CP12
WIP
CP6 HI-Pb
CP5 HI-Pb
CP4 EUT
CP3 EUT
CP2 Ni
CP1
ECD
ECD
ECD
ECD
ECD
SPRAY
TANK 2
120L HI-LEAD
TANK 3
120L EUTECTIC
TANK 4
48L Cu
TANK 1
48L Ni
WIP
TANK LAYOUT